



PATENT

Atty. Dkt. No. AMAT/2601.P11/CMP/ECF/RKK

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Mok, et al.

Serial No.: 09/785,815

Confirmation No.: 4127

Filed: February 16, 2001

For: INTEGRATED
SEMICONDUCTOR
SUBSTRATE BEVEL
CLEANING APPARATUS AND
METHOD

Group Art Unit: 1763

Examiner: Sylvia R. MacArthur

MAIL STOP AMENDMENT
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

CERTIFICATE OF MAILING
37 CFR 1.8

I hereby certify that this correspondence is being deposited on
July 6, 2004 with the United States Postal Service as First
Class Mail in an envelope addressed to: Commissioner for
Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

7/3/04
Date[Signature]
Signature

Dear Sir:

RESPONSE TO OFFICE ACTION DATED APRIL 13, 2004

In response to the Office Action dated April 13, 2004, having a shortened statutory period for response set to expire on July 13, 2004, please enter this response and reconsider the claims pending in the application for reasons discussed below. The Commissioner is hereby authorized to charge counsel's Deposit Account No. 20-0782/APPM/2601.P11/KMT, the fee of \$86.00 for one additional independent claim. If any additional fees are due in connection with this response, the Commissioner is hereby authorized to charge counsel's Deposit Account No. 20-0782/APPM/2601.P11/KMT, for any fees, including extension of time fees or excess claim fees, required to make this response timely and acceptable to the Office.

Amendments to the Specification begin on page 2 of this paper. **Amendments to the Claims** are reflected in the listing of claims which begins on page 3 of this paper. **Remarks** begin on page 8 of this paper.

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